



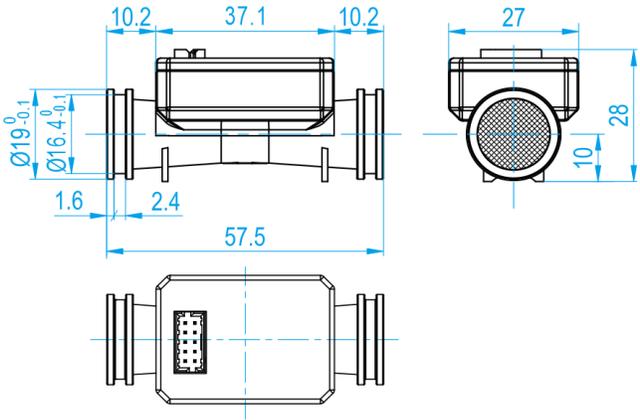
MEMS mass flow sensors

With Thermal-D sensing technology

FS1100 Series

FS1100 series mass flow sensors are manufactured with Siargo’s proprietary MEMS (micro-electro-mechanical systems) calorimetry with diffusivity sensing technologies (**Thermal-D®**) that measures the calorimetry and diffusivity of the flow medium. This technology compared to conventional calorimetric sensing offers much better linearity in the full dynamic range, removes gas sensitivities for gases that have similar thermal diffusivities, and increases the measurement accuracy when used with a gas conversion factor. It also simultaneously outputs the instant flow medium temperature data and improves the temperature performance of the thermal sensing approach.

Dimensions



Siargo Ltd.
Santa Clara, California
www.Siargo.com
408.969.0368
info@Siargo.com

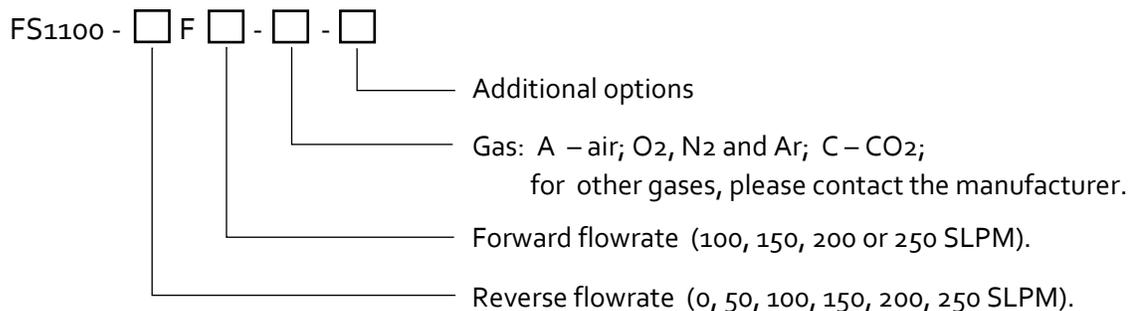


Specifications

Flow range	-250 ~ +250	SLPM
Accuracy (total error band)	$\pm(2.0+0.5FS)$	%
Repeatability	0.5	%
Response time	5	msec
Temperature range	-20 ~ +80	°C
Temperature accuracy (0 ~ 50 °C)	± 2.5	°C
Power supply	5 ($\pm 5\%$)	Vdc
Output	Linear, Analog: 0.5 ~ 2.5Vdc / Digital: I ² C	
Working temperature	-10 ~ +55	°C
Temperature coefficient	± 0.12	%/°C
Pressure rating	0.2	MPa
Warm-up time	500	msec
Humidity	<95 (no condensation)	%RH
Analog null shift	± 30	mVdc
Maximum overflow	300	SLPM
Maximum flow change	40	SLPM/sec

Note: Parameters specified at the calibration conditions: 20°C, 101.325kPa.

Product selection



- Note 1.** The default unit of the flow rate is SLPM. For other ranges, please contact the manufacturer.
- 2.** Example: FS1100-50F250-A is a sensor that measures mass flow rate from reverse 50 to forward 250SLPM, air.